Abstract

The present invention provides a wafer conveying system. The wafer conveying system comprises a wafer library, a manipulator, a wafer loading deviation detection module, and a wafer loading deviation compensation module; the manipulator is configured for taking out a wafer from the wafer library and conveying the wafer to a preset station; the wafer loading deviation detection module is configured for obtaining a wafer loading deviation of the wafer at the preset station; the wafer loading deviation compensation module calculates a position deviation of the wafer at a handover station of the manipulator and a worktable on the basis of the wafer loading deviation, the worktable moves to the handover station and the position is adjusted on the basis of the position deviation, and the manipulator conveys the wafer to the handover station; or the wafer loading deviation compensation module calculates a wafer loading path of the manipulator from the preset station to the handover station of the manipulator and the worktable on the basis of the wafer loading deviation, and the manipulator moves to the handover station according to the wafer loading path and conveys the wafer to the worktable. Compensating for the wafer loading deviation of the wafer by using the present invention is beneficial to reducing the cost. The present invention further provides a wafer conveying method and a defect detection device.